

## **PRISM ARRAY WITH TWO MAGNETIC SECTORS PER ARM**

### **Abstract of the Disclosure**

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One embodiment disclosed relates to an apparatus for inspecting a substrate using charged particles. The apparatus includes illumination optics, objective optics, projection optics, and a beam separator. The beam separator is configured to receive the incident beam from the illumination optics and bend the incident beam towards the objective optics, and also to receive the scattered beam from the objective optics and bend the scattered beam towards the projection optics. The beam separator comprises a magnetic prism array including a central magnetic sector, inner magnetic sectors outside the central sector, and outer magnetic sectors outside the inner sectors. Each of the inner and outer sectors may be configured to have its field strength independently adjustable for alignment and focusing purposes.

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